

**RETICLE CHUCKS AND METHODS FOR HOLDING A LITHOGRAPHIC  
RETICLE UTILIZING SAME**

**Abstract of the Disclosure**

5 Reticle-holding devices ("reticle chucks") are disclosed that define a  
downstream-facing reticle-mounting surface configured for holding an upstream-  
facing surface of a reticle for use in a microlithography apparatus. The reticle  
chucks can include peripheral regions and struts that define respective portions of  
the reticle-mounting surface, thereby preventing reticle sag while still allowing the  
10 axial distance from the reticle to a projection-optical system to be measured by  
grazing incidence without obstruction. The reticle can be held by, e.g., electrostatic  
attraction or vacuum suction to the reticle-mounting surface. The subject chucks  
also can be used for holding a reticle blank while inscribing a pattern on the reticle  
15 blank.

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